



(19)

(11) Publication number:

Generated Document.

## PATENT ABSTRACTS OF JAPAN

(21) Application number: 62177415

(51) Intl. Cl.: H01L 21/22

(22) Application date: 16.07.87

JP1020615A

BEST AVAILABLE COPY

(30) Priority:

(43) Date of application  
publication: 24.01.89(84) Designated contracting  
states:

(71) Applicant: TOSHIBA CERAMICS

(72) Inventor: YAMAGUCHI MASA  
TANADA YOSHINOBU  
TANAKA TAKASHI

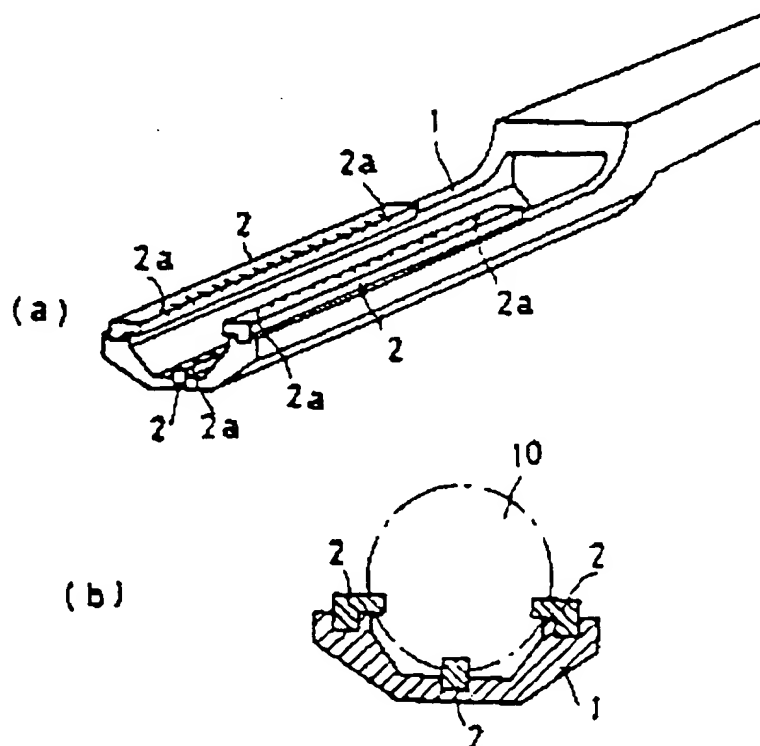
(74) Representative:

**(54) CANTILEVER FOR  
SEMICONDUCTOR  
TREATMENT**

(57) Abstract:

**PURPOSE:** To eliminate a deflection and a decrease in a strength by detachably attaching a plurality of quartz glass rods, each with many wafer supporting grooves formed in it, on a cantilever body made of silicon carbide, a jig for semiconductor diffusion.

**CONSTITUTION:** The end of a cantilever body 1 made of silicon carbide is formed in a recess corresponding to the shape of a wafer, and three engaging grooves, two of which are at the upper end and one of which is at a bottom, are formed along a longitudinal direction. A quartz glass rod 2 formed with many wafer supporting grooves 2a is detachably attached to the grooves, and a wafer 10 is supported by the grooves 2a. Thus, since a wafer boat



is not used, the deflection of a cantilever does not almost become a problem, and since the supporting groove is not formed on the body, its strength is not decreased. Further, since the rod 2 is detachable, it can be easily cleaned and replaced.

COPYRIGHT: (C)1989,JPO&Japio

BEST AVAILABLE COPY